

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Thomas A. Figura et al.

Title: USE OF A PLASMA SOURCE TO FORM A LAYER DURING THE FORMATION OF A SEMICONDUCTOR DEVICE

Docket No.: 303.932US4

Serial No.: 09/471,460

Filed: December 22, 1999

Due Date: May 14, 2007

Examiner: Calvin Lee

Group Art Unit: 2818

MS Amendment

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

We are transmitting herewith the following attached items (as indicated with an "X"):

Amendment and Response (9 pgs.).
 Communication Concerning Related Applications (1 pg.).

If not provided for in a separate paper filed herewith, Please consider this a PETITION FOR EXTENSION OF TIME for sufficient number of months to enter these papers and please charge any additional fees or credit overpayment to Deposit Account No. 19-0743.



By _____
Atty: Timothy B. Clise
Reg. No. 40,957

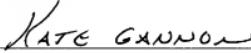
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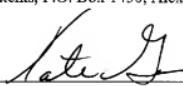
electronic filing system EFS-Web, and is addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

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Signature _____



SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A.
(GENERAL)

S/N 09/471,460

PATENT

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Serial No.: 09/471,460 Group Art Unit: 2818
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FORMATION OF A SEMICONDUCTOR DEVICE

COMMUNICATION CONCERNING RELATED APPLICATION(S)

MS Amendment

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Applicants would like to bring to the Examiner's attention the following related application(s) in the above-identified patent application:

<u>Serial/Patent No.</u>	<u>Filing Date/Issue Date</u>	<u>Attorney Docket</u>	<u>Title</u>
11651158	January 9, 2007	303.932US7	USE OF A PLASMA SOURCE TO FORM A LAYER DURING THE FORMATION OF A SEMICONDUCTOR DEVICE

Continuations and divisionals may be later filed on the cases listed above, or cited to the Examiner in any previous Communication Concerning Related Applications. Applicants request that the Examiner review all continuations and divisionals of the above-listed or previously-cited patent applications before allowing the claims of the present patent application.

Respectfully submitted,

THOMAS A. FIGURA ET AL.

By Applicants' Representatives,

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Date 14 May '07 By 
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Kate Gannon
Name

Nate J
Signature